

1 said controlling step includes setting the pressure of the gas in the range of about 0
2 torr to about 10 torr.

1 63. The method of claim 59 wherein:
2 said controlling step includes setting the pressure of the gas at about 1 torr.

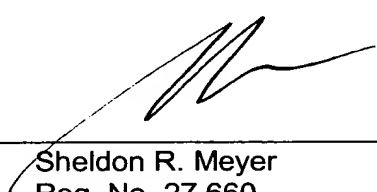
1 64. The method of claim 59 wherein the etch process is carried out in a low
2 pressure etch reactor which operates in the millitorr range and wherein a gas is contained in
3 contact with the chuck, which gas is in the range of about 0 torr to about 10 torr and is preferably
4 about 1 torr.

REMARKS

It is believed that all claims in the application should be patentable, and a Notice of Allowance is requested. The Commissioner is authorized to charge any underpayment or credit any overpayment to Deposit Account No. 06-1325 for any matter in connection with this Preliminary Amendment.

Respectfully submitted,

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By: 
Sheldon R. Meyer
Reg. No. 27,660

FLIESLER DUBB MEYER & LOVEJOY LLP
Four Embarcadero Center, Suite 400
San Francisco, California 94111-4156
Telephone: (415) 362-3800